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1-23-03  
Jal  
Attorney Docket no: SEL 246

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Koichiro TANAKA

Serial No.: 09/812,529

Filed: March 20, 2001

For: Method of Manufacturing A Semiconductor Device

Examiner: R. Booth

Art Unit: 2812

Commissioner for Patents  
Washington D.C. 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: the Assistant Commissioner for Patents, Washington, D.C. 20231 on December 20, 2002  
(Date of Deposit)

Rachelle Hammerquist  
Name of applicant, assignee, or Registered Rep.  
Rachelle Hammer 12-20-02  
Signature Date

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AMENDMENT B

In furtherance of the Notice of Allowance of September 23, 2002, a RCE and IDS being submitted herewith, please amend the above-identified application as follows:

IN THE CLAIMS:

Please add the following new claims:

14 (New). A method of manufacturing a semiconductor device, comprising:  
forming an amorphous semiconductor film over a substrate;  
irradiating the amorphous semiconductor film with a first laser beam to form a first crystalline semiconductor film; and  
irradiating the first crystalline semiconductor film with a second laser beam to form a second